

FIG. 1

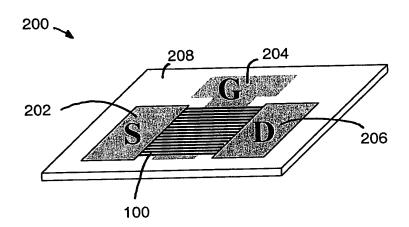


FIG. 2

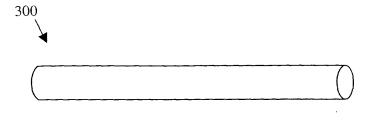


FIG. 3A

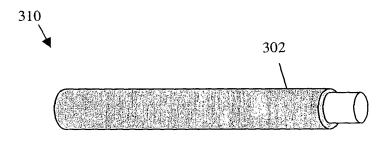


FIG. 3B



FIG. 3C

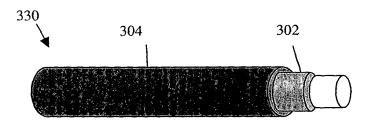


FIG. 3D

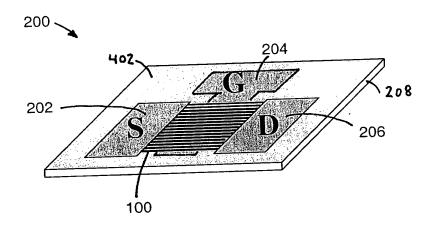


FIG. 4A

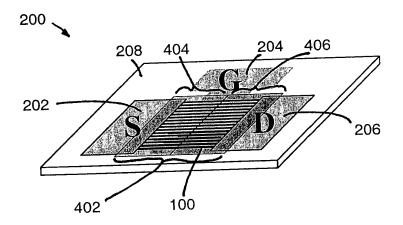


FIG. 4B

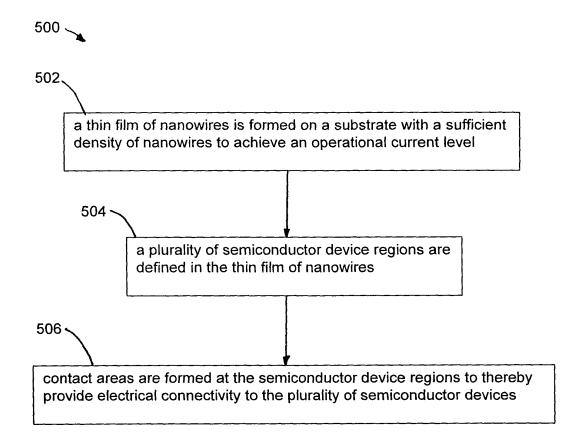


FIG. 5

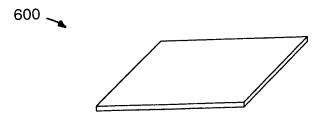


FIG. 6A

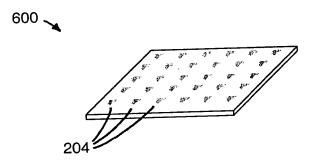


FIG. 6B

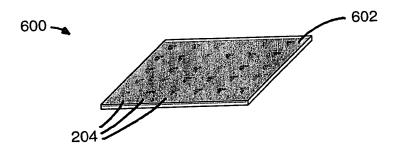


FIG. 6C

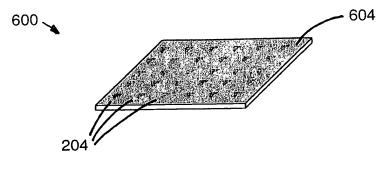


FIG. 6D

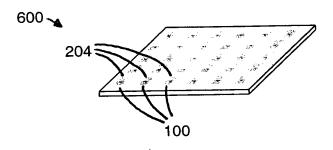


FIG. 6E

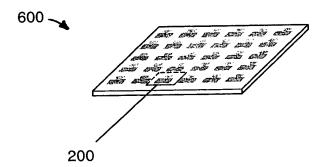


FIG. 6F

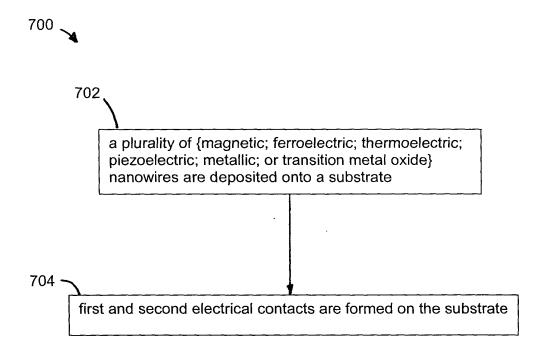
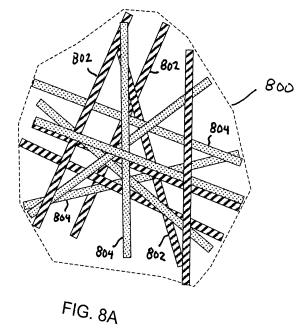


FIG. 7



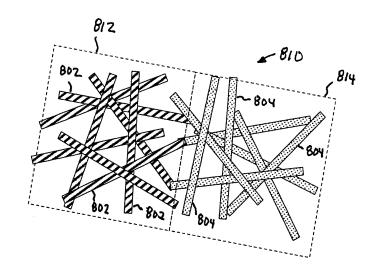


FIG. 8B

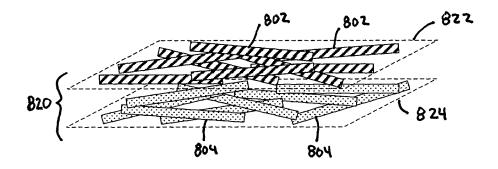


FIG. 8C



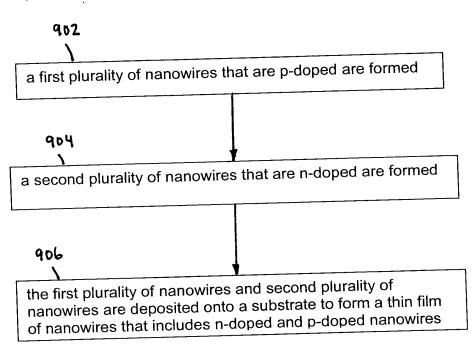


FIG. 9

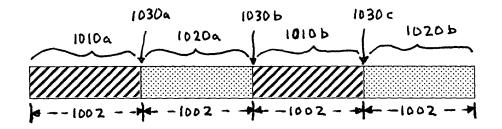


FIG. 10

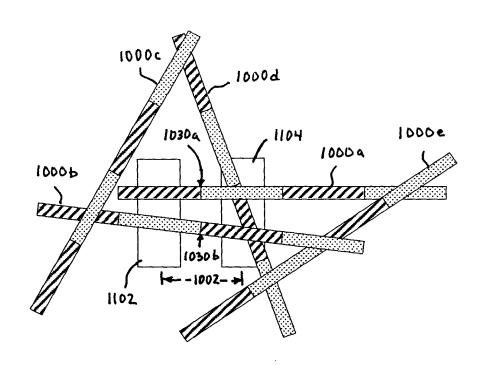


FIG. 11A



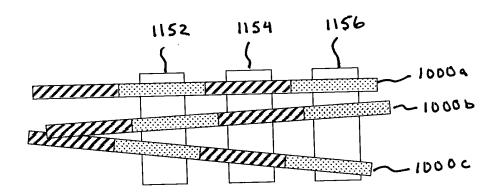


FIG. 11B

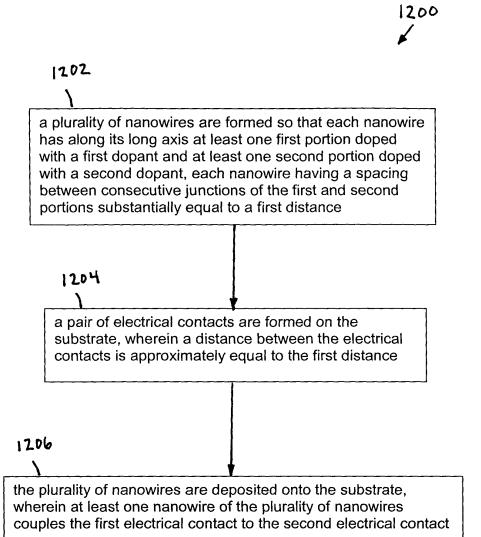


FIG. 12

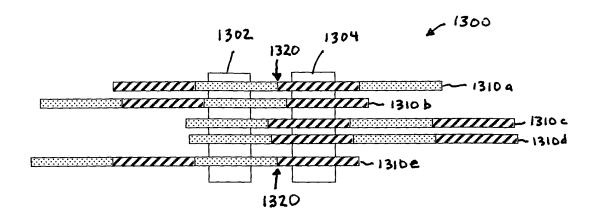


FIG. 13A

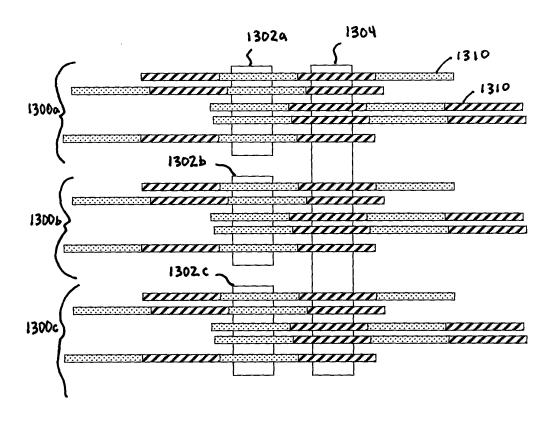


FIG. 13B

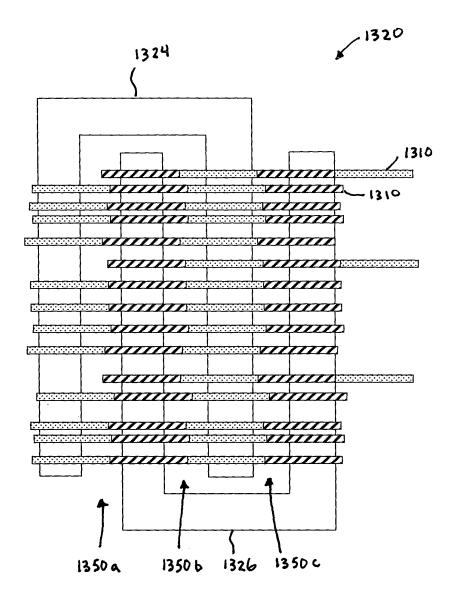


FIG. 13C



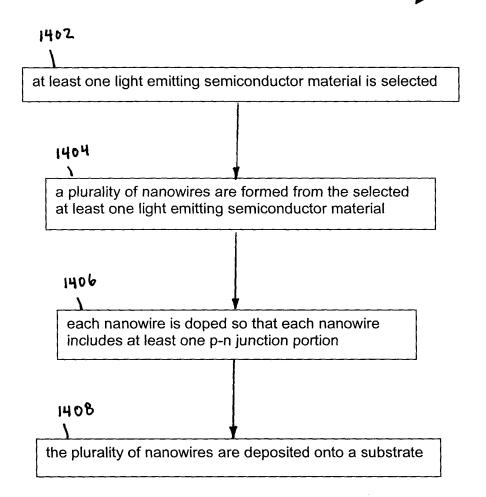


FIG. 14

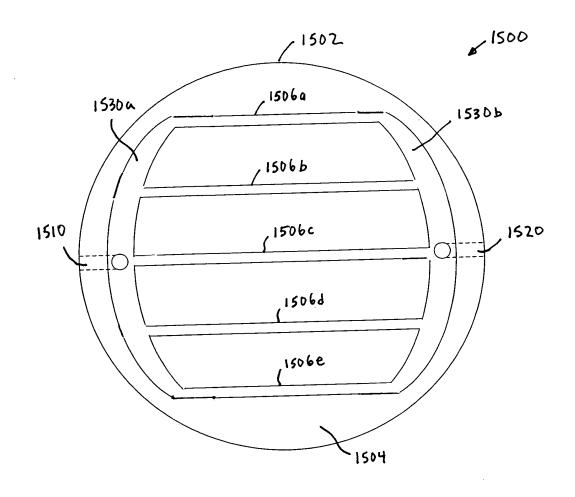
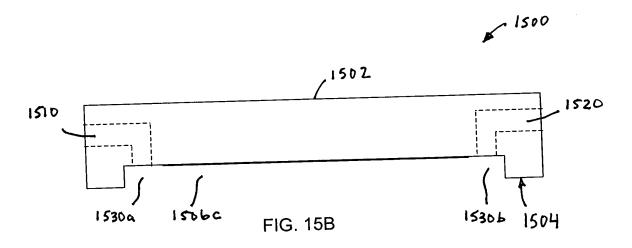


FIG. 15A



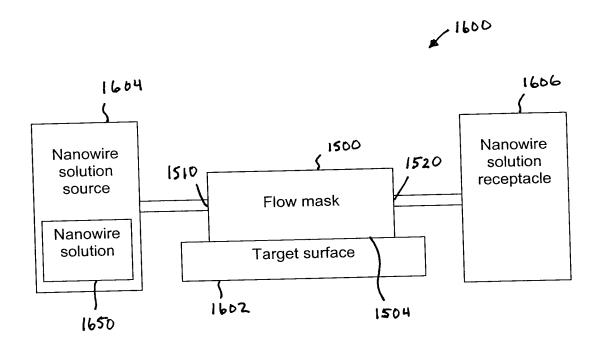


FIG. 16

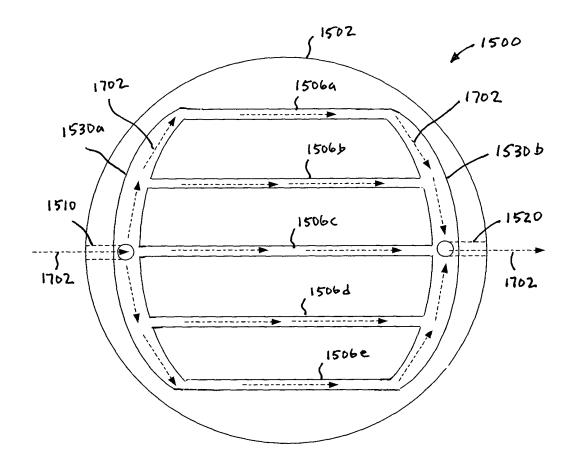
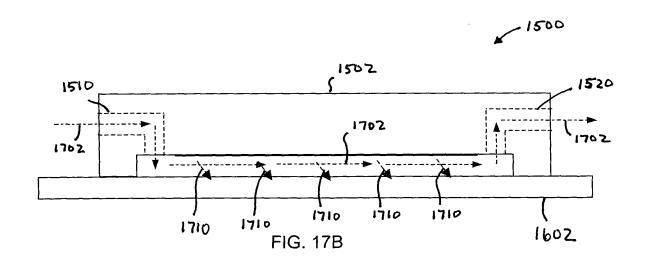


FIG. 17A



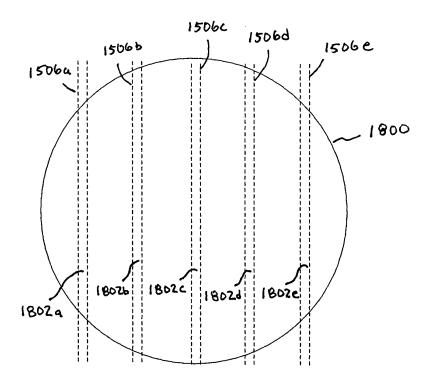


FIG. 18A

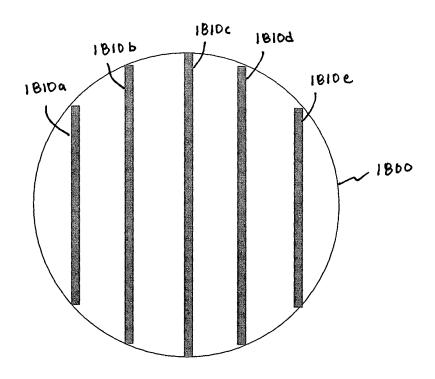


FIG. 18B

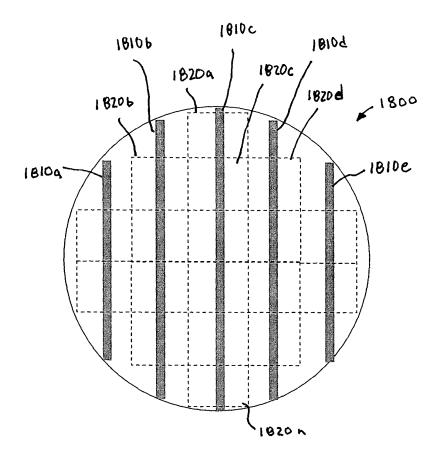
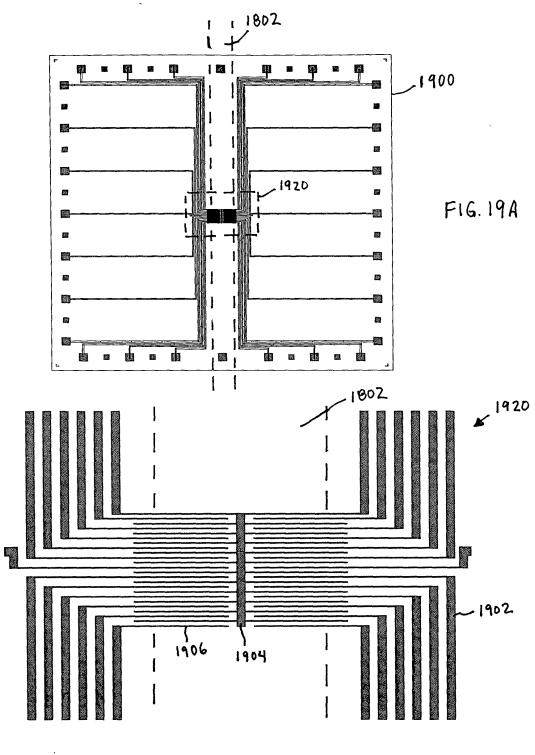


FIG. 18C



F16.19B

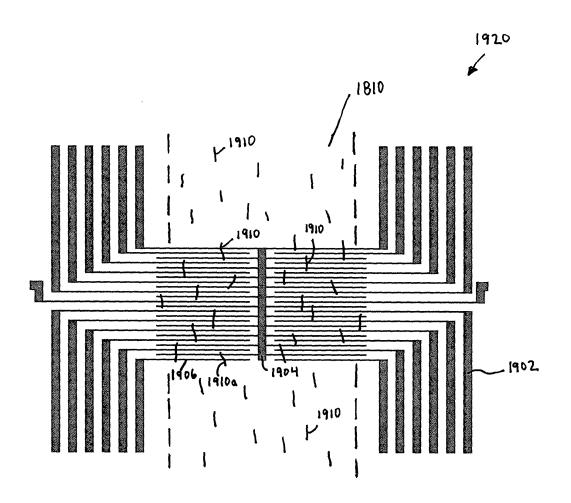
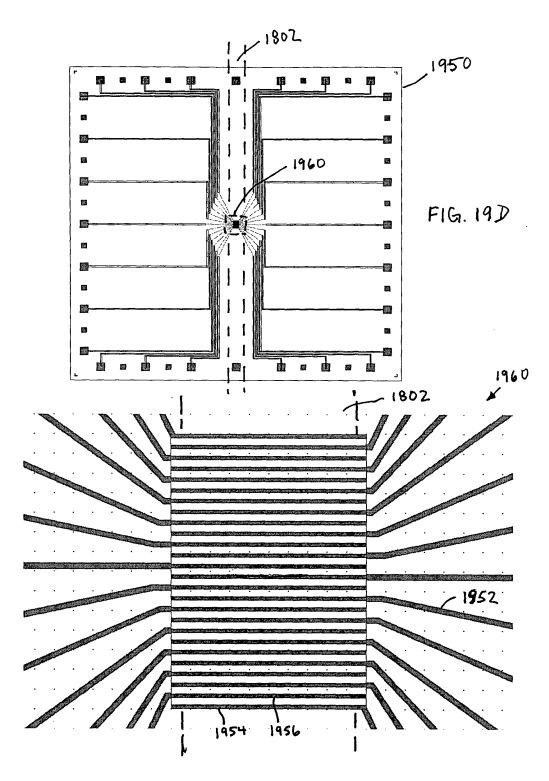


FIG. 190



F16. 19E

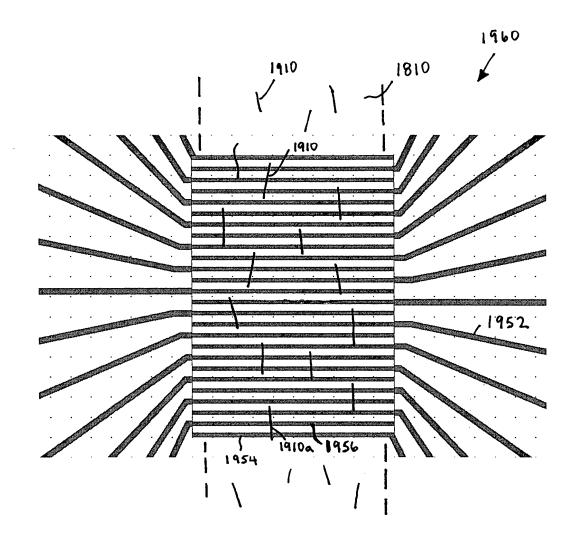
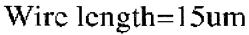


FIG. 19F



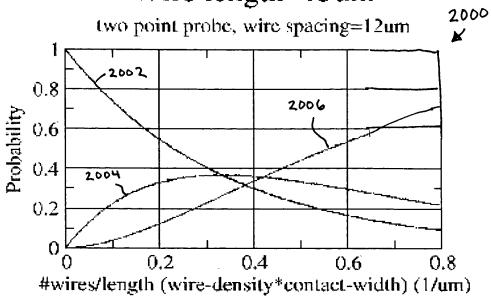


FIG. 20 A



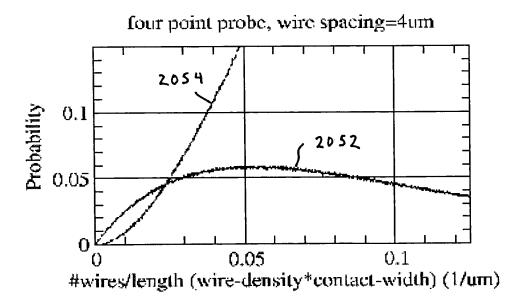


FIG. 20B

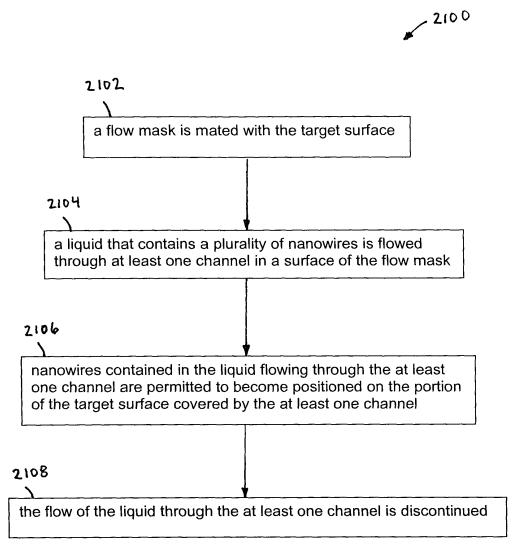


FIG. 21

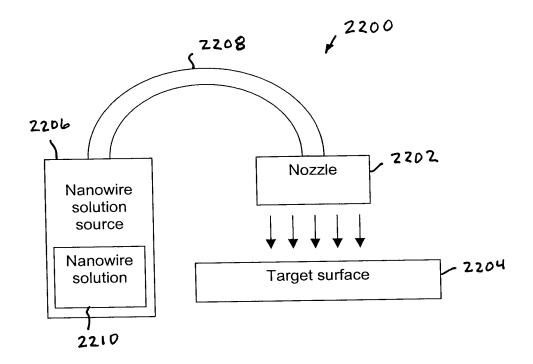


FIG. 22

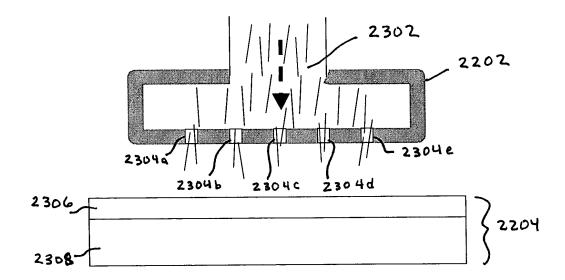


FIG. 23

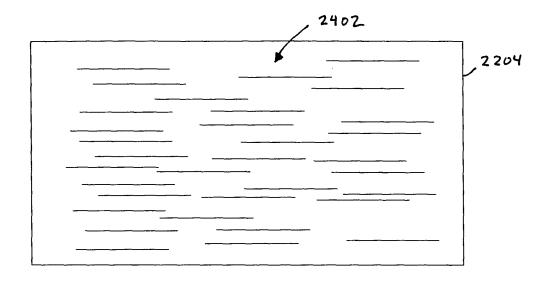


FIG. 24

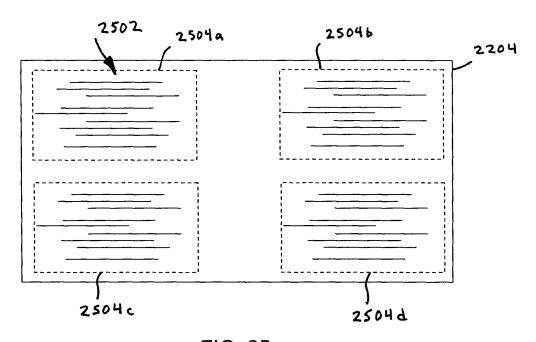


FIG. 25

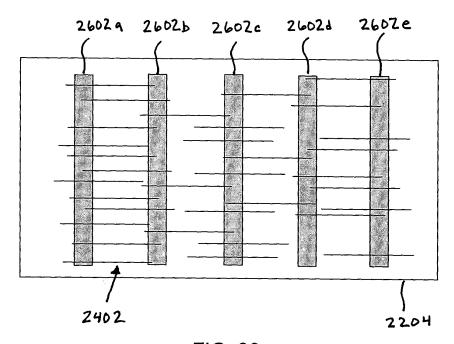


FIG. 26

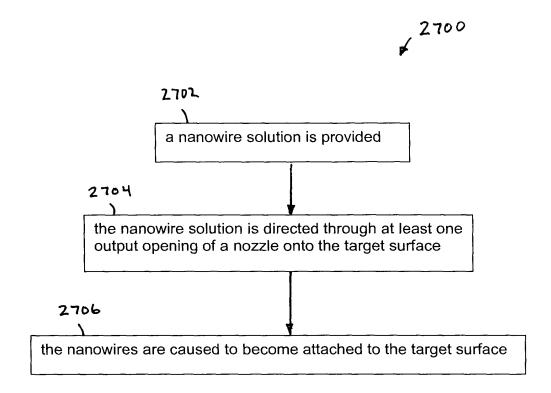


FIG. 27



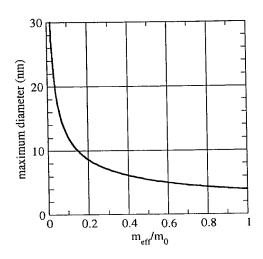


FIG. 28

		2900
2902	2904 (2906 ^{\$}
	7	David san E (aV)
Semiconductor	Effective mass meff/m ₀	Band gap E _g (eV)
Diamond	0.57	5.5
Si	0.33	1.14
Ge	0.2	0.67
AlN	0.4	6.2
AlSb	0.12	1.58
GaN	0.13	3.2
GaP	0.38	2.9
GaAs	0.067	1.5
GaSb	0.041	0.72
InN	0.11	2.0
InP	0.07	1.29
InAs	0.02	0.33
InSb	0.013	0.16
ZnO	0.27	3.35
Zns	0.40	3.68

FIG. 29

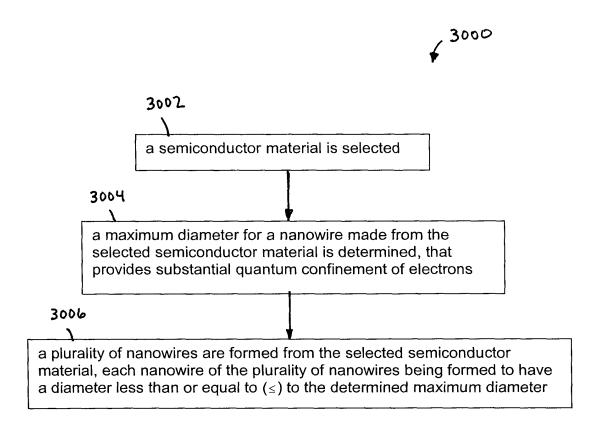


FIG. 30

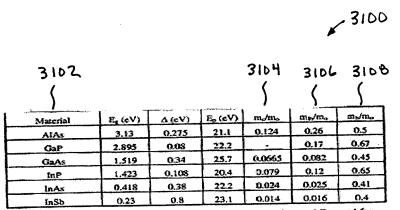


Table 1.1. Parameters for various zinc blende III - V semiconductors (all quoted for low temperature). (Note: all values are for the direct gap at zone center, though AlAs and GaP are indirect gap semiconductors, having lower conduction band minima away from zone center.)

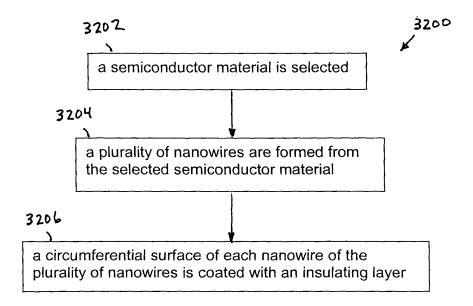


FIG. 32

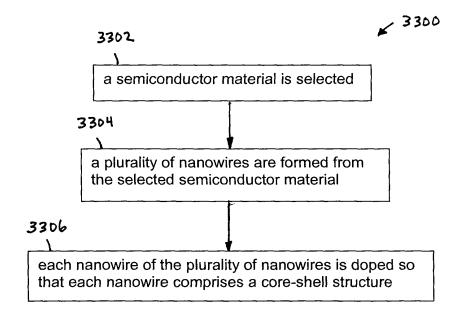
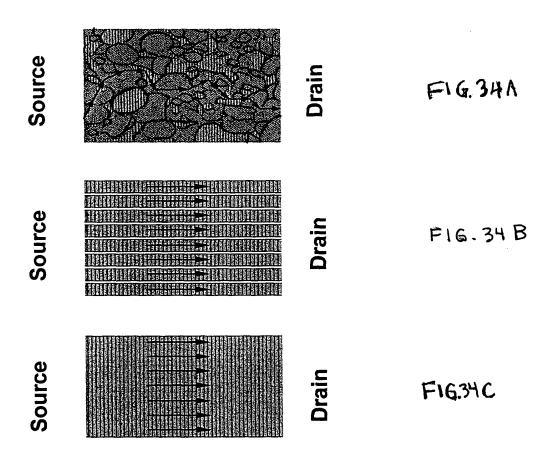


FIG. 33



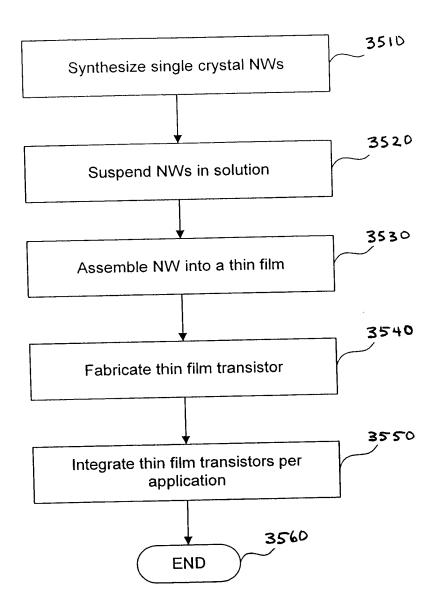
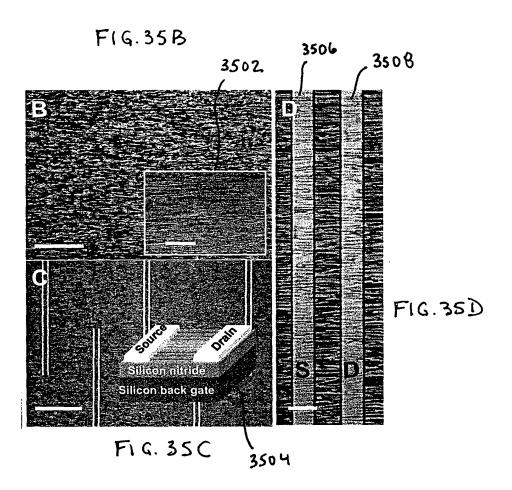


FIG. 35 A



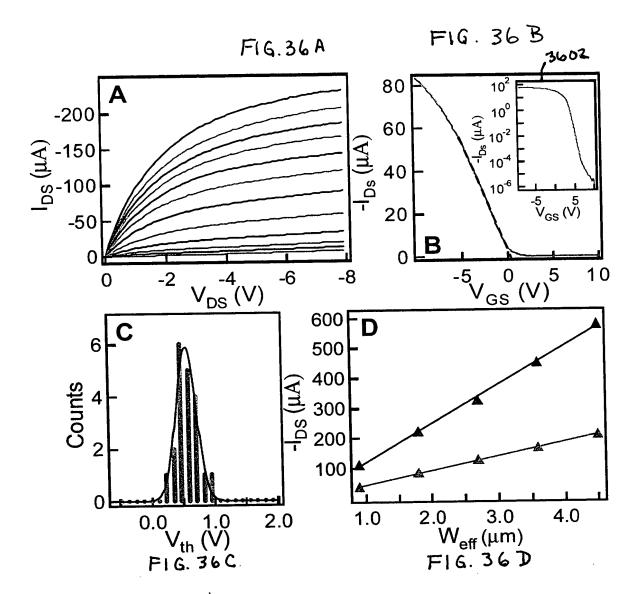
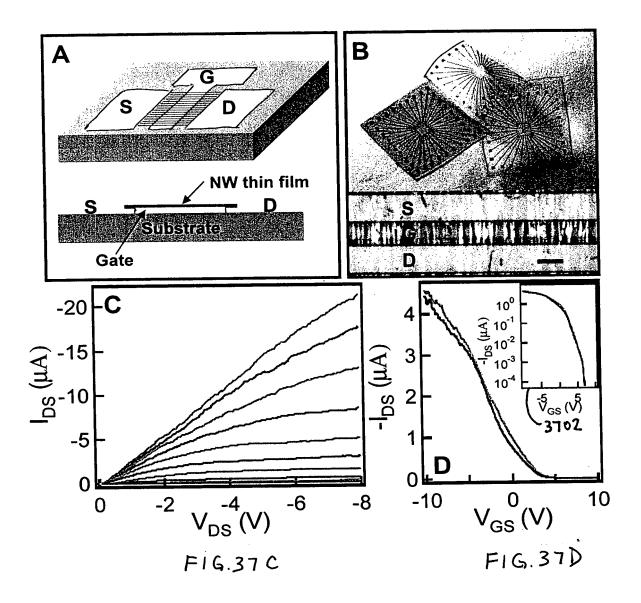
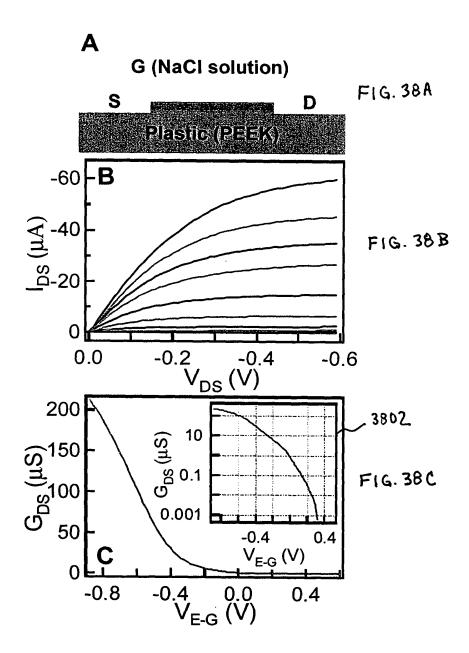
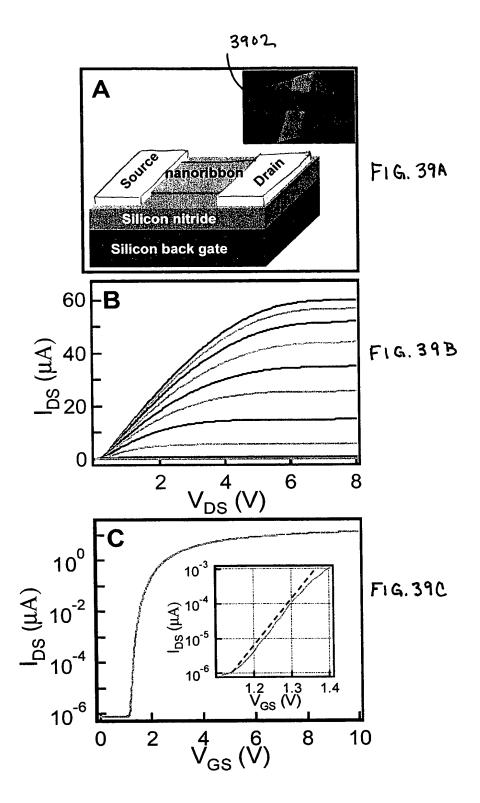


FIG. 37B







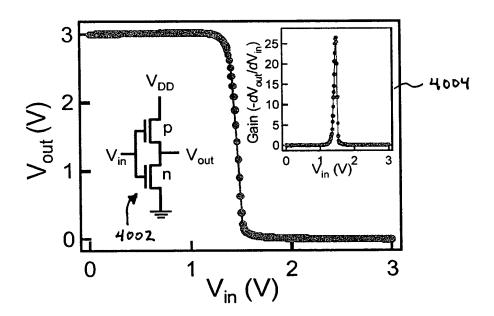
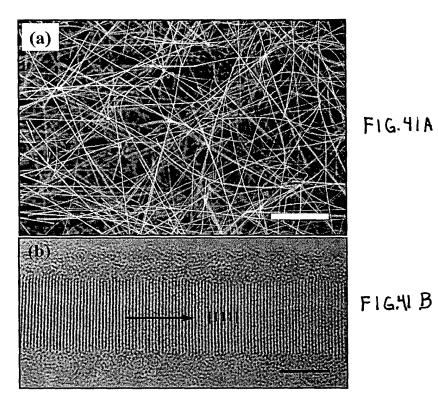
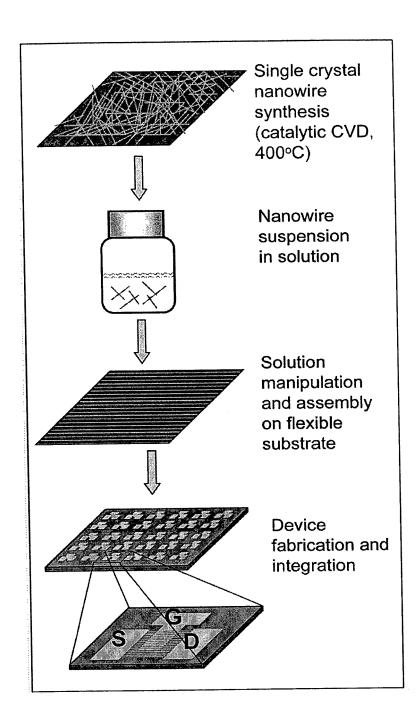
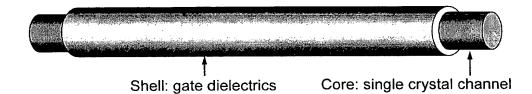


FIG. 40





F1G. 42



F1G.43

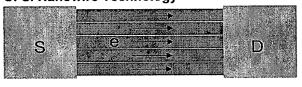
A: a-Si Technology



B: poly-Si Technology



C: Si Nanowire Technology



F16.44C

F16.44A

FIG.44B

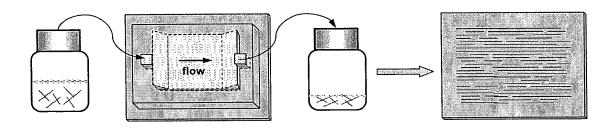
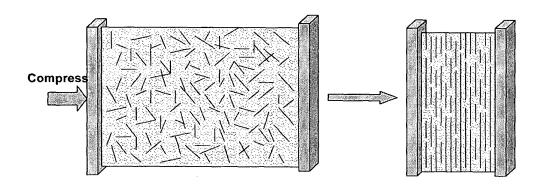
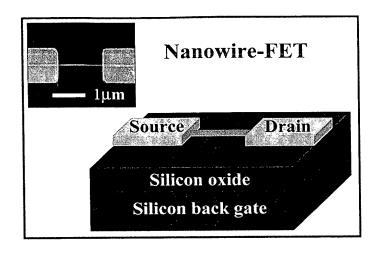


FIG. 45



F16.46



F1647

